

| | U | 1 | Document ID | Issue Date | Pages | Title | Current OR |
|---|-------------------------------------|--------------------------|-------------------------|------------|-------|--|------------|
| 1 | <input type="checkbox"/> | <input type="checkbox"/> | US 20030204826 A1 | 20031030 | 25 | Inspection method and inspection system using charged particle beam | 716/4 |
| 2 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20030164460 A1 | 20030904 | 19 | Patterned wafer inspection method and apparatus therefor | 250/492.3 |
| 3 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20030155508 A1 | 20030821 | 28 | Workpiece holder, semiconductor fabricating apparatus, semiconductor inspecting apparatus, circuit pattern inspecting apparatus, charged particle beam application apparatus, calibrating substrate, workpiece holding method, circuit pattern inspecting method, and charged particle beam application method | 250/310 |
| 4 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20030146382 A1 | 20030807 | 28 | Workpiece holder, semiconductor fabricating apparatus, semiconductor inspecting apparatus, circuit pattern inspecting apparatus, charged particle beam application apparatus, calibrating substrate, workpiece holding method, circuit pattern inspecting method, and charged particle beam application method | 250/310 |
| 5 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20030118149 A1 | 20030626 | 28 | Defect inspection apparatus and defect inspection method | 378/58 |
| 6 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20030111616 A1 | 20030619 | 28 | Workpiece holder, semiconductor fabricating apparatus, semiconductor inspecting apparatus, circuit pattern inspecting apparatus, charged particle beam application apparatus, calibrating substrate, workpiece holding method, circuit pattern inspecting method, and charged particle beam application method | 250/492.2 |

| | Current XRef | Retrieval Classif | Inv ntor | S | C | P | 2 | 3 | 4 | 5 |
|---|-----------------|----------------------|--------------------------------|-------------------------------------|--------------------------|--------------------------|--------------------------|--------------------------|--------------------------|--------------------------|
| 1 | 716/19 | | Nishiyama, Hidetoshi et al. | <input checked="" type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 2 | | | Shinada, Hiroyuki et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 3 | | | Suzuki, Hiroyuki et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 4 | 250/252.1 | | Suzuki, Hiroyuki et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 5 | | | Okuda, Hirohito et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 6 | 250/442.11 | | Suzuki, Hiroyuki et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |

| | Image Doc. Displayed | PT |
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| 1 | US 20030204826 | <input type="checkbox"/> |
| 2 | US 20030164460 | <input type="checkbox"/> |
| 3 | US 20030155508 | <input type="checkbox"/> |
| 4 | US 20030146382 | <input type="checkbox"/> |
| 5 | US 20030118149 | <input type="checkbox"/> |
| 6 | US 20030111616 | <input type="checkbox"/> |

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|----|-------------------------------------|--------------------------|-------------------------|-----------|-------|---|------------|
| 7 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20030094572 A1 | 20030522 | 21 | Inspection system and inspection process for wafer with circuit using charged-particle beam | 250/310 |
| 8 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20030076989 A1 | 20030424 | 27 | Automated repetitive array microstructure defect inspection | 382/145 |
| 9 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20030057971 A1 | 20030327 | 20 | Inspection method using a charged particle beam and inspection device based thereon | 324/751 |
| 10 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20030003611 A1 | 20030102 | 21 | Apparatus and methods for monitoring self-aligned contact arrays | 438/16 |
| 11 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20020148961 A1 | 20021017 | 104 | Electron beam apparatus and device production method using the electron beam apparatus | 250/311 |
| 12 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20020117635 A1 | 20020829 | 19 | PATTERNED WAFER INSPECTION METHOD AND APPARATUS THEREFOR | 250/492.3 |
| 13 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20020070738 A1 | 20020613 | 24 | Semiconductor device inspecting apparatus | 324/751 |
| 14 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20020028399 A1 | 20020307 | 102 | Inspection system by charged particle beam and method of manufacturing devices using the system | 430/30 |
| 15 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20020024021 A1 | 20020228 | 27 | Method and apparatus for inspecting patterns of a semiconductor device with an electron beam | 250/492.3 |
| 16 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 20010016938 A1 | 20010823 | 25 | Inspection method and inspection system using charged particle beam | 716/21 |
| 17 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 6614244 B2 | 20030902 | 23 | Semiconductor device inspecting apparatus | 324/751 |
| 18 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 6512227 B2 | 20030128 | 25 | Method and apparatus for inspecting patterns of a semiconductor device with an electron beam | 250/310 |

| | Current XRef | Retrieval Classif | Inventor | S | C | P | 2 | 3 | 4 | 5 |
|----|-----------------------------------|----------------------|-----------------------------|--------------------------|--------------------------|--------------------------|--------------------------|--------------------------|--------------------------|--------------------------|
| 7 | 250/306 | | Matsui, Miyako et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 8 | | | Maayah, Kais Jameel et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 9 | | | Nishiyama, Hidetoshi et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 10 | | | Weiner, Kurt H. et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 11 | | | Nakasuji, Mamoru et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 12 | | | SHINADA, HIROYUKI et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 13 | 250/310 | | Yamada, Keizo et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 14 | 250/306; 356/237.5; 430/296 | | Nakasuji, Mamoru et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 15 | | | Iwabuchi, Yuko et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 16 | 716/4 | | Nishiyama, Hidetoshi et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 17 | | | Yamada, Keizo et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 18 | | | Iwabuchi, Yuko et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |

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| 9 | US 20030057971 | <input type="checkbox"/> |
| 10 | US 20030003611 | <input type="checkbox"/> |
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| 12 | US 20020117635 | <input type="checkbox"/> |
| 13 | US 20020070738 | <input type="checkbox"/> |
| 14 | US 20020028399 | <input type="checkbox"/> |
| 15 | US 20020024021 | <input type="checkbox"/> |
| 16 | US 20010016938 | <input type="checkbox"/> |
| 17 | US 6614244 | <input type="checkbox"/> |
| 18 | US 6512227 | <input type="checkbox"/> |

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| 19 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 6509564 B1 | 20030121 | 30 | WORKPIECE HOLDER, SEMICONDUCTOR FABRICATING APPARATUS, SEMICONDUCTOR INSPECTING APPARATUS, CIRCUIT PATTERN INSPECTING APPARATUS, CHARGED PARTICLE BEAM APPLICATION APPARATUS, CALIBRATING SUBSTRATE, WORKPIECE HOLDING METHOD, CIRCUIT PATTERN INSPECTING METHOD, AND CHARGED PARTICLE BEAM APPLICATION METHOD | 250/310 |
| 20 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 6465783 B1 | 20021015 | 22 | High-throughput specimen-inspection apparatus and methods utilizing multiple parallel charged particle beams and an array of multiple secondary-electron-dete ctors | 250/311 |
| 21 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US 6452677 B1 | 20020917 | 20 | Method and apparatus for detecting defects in the manufacture of an electronic device | 356/394 |
| 22 | <input checked="" type="checkbox"/> | <input type="checkbox"/> | US RE33193 E | 19900403 | 21 | Ion beam processing apparatus and method of correcting mask defects | 250/309 |
| 23 | <input type="checkbox"/> | <input checked="" type="checkbox"/> | US 4761607 A | 19880802 | 13 | Apparatus and method for inspecting semiconductor devices | 324/752 |
| 24 | <input type="checkbox"/> | <input checked="" type="checkbox"/> | US 4503329 A | 19850305 | 19 | Ion beam processing apparatus and method of correcting mask defects | 250/309 |
| 25 | <input type="checkbox"/> | <input checked="" type="checkbox"/> | US 4357540 A | 19821102 | 10 | Semiconductor device array mask inspection method and apparatus | 250/491.1 |

| | Current XRef | Retrieval Classif | Inventor | S | C | P | 2 | 3 | 4 | 5 |
|----|---|----------------------|---------------------------------|-------------------------------------|--------------------------|--------------------------|--------------------------|--------------------------|--------------------------|--------------------------|
| 19 | 250/491.1 | | Suzuki, Hiroyuki et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 20 | 250/306; 250/307; 250/310 | | Nakasuji, Mamoru | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 21 | 250/307; 250/310; 356/237.3; 356/237.4; 356/388 | | Do, Douglas et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 22 | 250/492.2 | | Yamaguchi, Hiroshi et al. | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 23 | 324/765; 714/724; 714/732 | | Shiragasawa, Tsuyoshi et al. | <input checked="" type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 24 | 250/492.2; 257/E21.21 1 | | Yamaguchi, Hiroshi et al. | <input checked="" type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |
| 25 | 250/492.2 | | Benjamin, Charles E. et al. | <input checked="" type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> | <input type="checkbox"/> |

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| 19 | US 6509564 | <input type="checkbox"/> |
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| 22 | US RE33193 | <input type="checkbox"/> |
| 23 | US 4761607 | <input type="checkbox"/> |
| 24 | US 4503329 | <input type="checkbox"/> |
| 25 | US 4357540 | <input type="checkbox"/> |

| | Type | L # | Hits | S arch Text | DBs | Time Stamp | Comments |
|----|------|-----|------|---|----------------------------|------------------|----------|
| 1 | IS&R | L1 | 0 | ("(electron or (charged adj particle) near3 beam\$2)) and (semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5) ".PN. | USPA T; US-P GPUB | 2004/03/08 11:26 | |
| 2 | BRS | L2 | 34 | (electron or (charged adj particle) near3 beam\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5)) | USPA T; US-P GPUB | 2004/03/08 11:34 | |
| 3 | BRS | L3 | 0 | L2 and (compar\$5 with ((defective or damaged) near2 (chip or circuit or device or die))) | USPA T; US-P GPUB | 2004/03/08 11:29 | |
| 4 | BRS | L4 | 1 | L2 and (compar\$5 with (defective or damaged)) | USPA T; US-P GPUB | 2004/03/08 11:36 | |
| 5 | BRS | L5 | 34 | (electron or (charged adj particle) near3 (beam\$2 or irradiation)) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5)) | USPA T; US-P GPUB | 2004/03/08 11:35 | |
| 6 | BRS | L7 | 1 | L6 and (compar\$5 with (defective or damaged).)) | USPA T; US-P GPUB | 2004/03/08 11:37 | |
| 7 | BRS | L8 | 1 | 20020130262.pn. | USPA T; US-P GPUB | 2004/03/08 11:37 | |
| 8 | BRS | L9 | 1 | L7 and (compar\$5 with (defective or damaged)) | USPA T; US-P GPUB | 2004/03/08 11:39 | |
| 9 | BRS | L6 | 8 | (secondary adj electron\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5)) | USPA T; US-P GPUB | 2004/03/08 11:40 | |
| 10 | BRS | L10 | 1 | L6 and (compar\$5 with (defective or damaged)) | USPA T; US-P GPUB | 2004/03/08 11:41 | |

| | Error Definition | Er ro rs |
|----|---------------------|----------------|
| 1 | | 0 |
| 2 | | 0 |
| 3 | | 0 |
| 4 | | 0 |
| 5 | | 0 |
| 6 | | 0 |
| 7 | | 0 |
| 8 | | 0 |
| 9 | | 0 |
| 10 | | 0 |

| | Type | L # | Hits | Search Text | DBs | Time Stamp | Comments |
|----|------|-----|------|---|----------------------------|----------------------|----------|
| 11 | BRS | L11 | 114 | (secondary adj electron\$2) and ((semiconductor near3 (chip\$2 or device\$2 or circuit\$2 or die\$2)) with (inspect\$4 near5 defect\$5)) | USPA T; US-P GPUB | 2004/03/0 8 11:41 | |
| 12 | BRS | L12 | 106 | L11 not L6 | USPA T; US-P GPUB | 2004/03/0 8 11:41 | |
| 13 | BRS | L13 | 25 | L12 and (compar\$5 with (defective or damaged)) | USPA T; US-P GPUB | 2004/03/0 8 11:45 | |
| 14 | BRS | L14 | 0 | L13 and ((increas\$7 near3 operation\$3 near3 parameter\$2) with (until near7 fail\$3)) | USPA T; US-P GPUB | 2004/03/0 8 11:48 | |
| 15 | BRS | L15 | 0 | L13 and ((inspect\$6) with (until near7 fail\$5)) | USPA T; US-P GPUB | 2004/03/0 8 11:48 | |
| 16 | BRS | L16 | 0 | L11 and ((inspect\$6) with (until near7 fail\$5)) | USPA T; US-P GPUB | 2004/03/0 8 11:49 | |
| 17 | BRS | L17 | 0 | L11 and ((inspect\$6) with (until near7 (fail\$5 or damaged))) | USPA T; US-P GPUB | 2004/03/0 8 11:49 | |
| 18 | BRS | L18 | 0 | L11 and ((operat\$6) with (until near7 (fail\$5 or damaged))) | USPA T; US-P GPUB | 2004/03/0 8 11:51 | |
| 19 | BRS | L19 | 21 | L11 and (until with (fail\$5 or damaged)) | USPA T; US-P GPUB | 2004/03/0 8 11:58 | |
| 20 | BRS | L20 | 0 | L13 and L19 | USPA T; US-P GPUB | 2004/03/0 8 11:55 | |

| | Error Definition | Er ro rs |
|----|---------------------|----------------|
| 11 | | 0 |
| 12 | | 0 |
| 13 | | 0 |
| 14 | | 0 |
| 15 | | 0 |
| 16 | | 0 |
| 17 | | 0 |
| 18 | | 0 |
| 19 | | 0 |
| 20 | | 0 |

| L Number | Hits | Search Text | DB | Time stamp |
|----------|------|---|-----------------|------------------|
| 1 | 0 | ("(electron or (charged adj particle) near3 beam\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5)) | USPAT; US-PGPUB | 2004/03/08 11:26 |
| 2 | 34 | (electron or (charged adj particle) near3 beam\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5)) | USPAT; US-PGPUB | 2004/03/08 11:34 |
| 3 | 0 | ((electron or (charged adj particle) near3 beam\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5))) and (compar\$5 with ((defective or damaged) near2 (chip or circuit or device or die))) | USPAT; US-PGPUB | 2004/03/08 11:29 |
| 4 | 1 | ((electron or (charged adj particle) near3 beam\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5))) and (compar\$5 with (defective or damaged)) | USPAT; US-PGPUB | 2004/03/08 11:36 |
| 5 | 34 | (electron or (charged adj particle) near3 (beam\$2 or irradiation)) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5)) | USPAT; US-PGPUB | 2004/03/08 11:35 |
| 7 | 1 | ((secondary adj electron\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5))) and (compar\$5 with (defective or damaged)) | USPAT; US-PGPUB | 2004/03/08 11:37 |
| 8 | 1 | 20020130262.pn. | USPAT; US-PGPUB | 2004/03/08 11:37 |
| 9 | 1 | ((secondary adj electron\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5))) and (compar\$5 with (defective or damaged)) | USPAT; US-PGPUB | 2004/03/08 11:39 |
| 6 | 8 | (secondary adj electron\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5)) | USPAT; US-PGPUB | 2004/03/08 11:40 |
| 10 | 1 | ((secondary adj electron\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5))) and (compar\$5 with (defective or damaged)) | USPAT; US-PGPUB | 2004/03/08 11:41 |
| 11 | 114 | (secondary adj electron\$2) and ((semiconductor near3 (chip\$2 or device\$2 or circuit\$2 or die\$2)) with (inspect\$4 near5 defect\$5)) | USPAT; US-PGPUB | 2004/03/08 11:41 |
| 12 | 106 | ((secondary adj electron\$2) and ((semiconductor near3 (chip\$2 or device\$2 or circuit\$2 or die\$2)) with (inspect\$4 near5 defect\$5))) not ((secondary adj electron\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5))) | USPAT; US-PGPUB | 2004/03/08 11:41 |
| 13 | 25 | ((secondary adj electron\$2) and ((semiconductor near3 (chip\$2 or device\$2 or circuit\$2 or die\$2)) with (inspect\$4 near5 defect\$5))) not ((secondary adj electron\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5)))) and (compar\$5 with (defective or damaged)) | USPAT; US-PGPUB | 2004/03/08 11:45 |
| 14 | 0 | ((secondary adj electron\$2) and ((semiconductor near3 (chip\$2 or device\$2 or circuit\$2 or die\$2)) with (inspect\$4 near5 defect\$5))) not ((secondary adj electron\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5)))) and (compar\$5 with (defective or damaged))) and ((increas\$7 near3 operation\$3 near3 parameter\$2) with (until near7 fail\$3)) | USPAT; US-PGPUB | 2004/03/08 11:48 |

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|----|----|---|--------------------|---------------------|
| 15 | 0 | ((((secondary adj electron\$2) and ((semiconductor near3 (chip\$2 or device\$2 or circuit\$2 or die\$2)) with (inspect\$4 near5 defect\$5))) not ((secondary adj electron\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5)))) and (compar\$5 with (defective or damaged))) and ((inspect\$6) with (until near7 fail\$5)) | USPAT; US-PGPUB | 2004/03/08 11:48 |
| 16 | 0 | ((secondary adj electron\$2) and ((semiconductor near3 (chip\$2 or device\$2 or circuit\$2 or die\$2)) with (inspect\$4 near5 defect\$5))) and ((inspect\$6) with (until near7 fail\$5)) | USPAT; US-PGPUB | 2004/03/08 11:49 |
| 17 | 0 | ((secondary adj electron\$2) and ((semiconductor near3 (chip\$2 or device\$2 or circuit\$2 or die\$2)) with (inspect\$4 near5 defect\$5))) and ((inspect\$6) with (until near7 (fail\$5 or damaged))) | USPAT; US-PGPUB | 2004/03/08 11:49 |
| 18 | 0 | ((secondary adj electron\$2) and ((semiconductor near3 (chip\$2 or device\$2 or circuit\$2 or die\$2)) with (inspect\$4 near5 defect\$5))) and ((operat\$6) with (until near7 (fail\$5 or damaged))) | USPAT; US-PGPUB | 2004/03/08 11:51 |
| 19 | 21 | ((secondary adj electron\$2) and ((semiconductor near3 (chip\$2 or device\$2 or circuit\$2 or die\$2)) with (inspect\$4 near5 defect\$5))) and (until with (fail\$5 or damaged)) | USPAT; US-PGPUB | 2004/03/08 11:58 |
| 20 | 0 | ((((secondary adj electron\$2) and ((semiconductor near3 (chip\$2 or device\$2 or circuit\$2 or die\$2)) with (inspect\$4 near5 defect\$5))) not ((secondary adj electron\$2) and ((semiconductor near3 chip\$2) with (inspect\$4 near5 defect\$5)))) and (compar\$5 with (defective or damaged))) and ((secondary adj electron\$2) and ((semiconductor near3 (chip\$2 or device\$2 or circuit\$2 or die\$2)) with (inspect\$4 near5 defect\$5))) and (until with (fail\$5 or damaged))) | USPAT; US-PGPUB | 2004/03/08 11:55 |